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**RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCESSING  
EXAMINING GROUP ART UNIT 2621**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Jong-won Lee et al.

Docket: 8021-55 (SS-14743-US)

Serial No.: 09/899,627

Group Art Unit: 2822

Filed: July 5, 2001

Examiner: Guerrero, Maria F.

For: **SOLUTION FOR CHEMICAL MECHANICAL POLISHING AND  
METHOD OF MANUFACTURING COPPER METAL  
INTERCONNECTION LAYER USING THE SAME**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE UNDER 37 C.F.R. § 1.116**

In reply to the Final Office Action dated June 22, 2005, please reconsider the above-identified application in light of the following amendments and remarks.

**CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)**

I hereby certify that this correspondence (and any document referred to as being attached or enclosed) is being deposited with the United States Postal Service as first class mail, postage paid in an envelope addressed to: Mail Stop AF, Commissioner for Patents, PO Box 1450, Alexandria VA 22313-1450 on September 19, 2005.

Dated: 9/19/05

David L. Heath  
David L. Heath